

## Claims

1. (Original) A process meter (10), particularly a field meter, comprising:
  - a sensor (20) which can be mounted in a wall (9) of a vessel for holding or conveying a process medium, particularly in a wall of a pipe or tank; and
  - an electronics case (30) for meter electronics (50) which is mechanically, particularly rigidly, coupled to the sensor (20),
  - wherein the electronics case (30) is at least intermittently subjected to vibrations generated in or transmitted via the sensor (20), and
  - wherein, in order to reduce amplitudes of possible vibrations of the electronics case (30), at least one vibration absorber (60) which is vibrated at least intermittently in order to dissipate vibrational energy taken into the electronics case (30) is affixed to a wall (31) of the electronics case.
2. (Original) A process meter as set forth in claim 1 wherein the vibration absorber (60) is positioned at a distance, particularly as far as possible, from a joint (14) between the sensor (20) and the electronics case (30).
3. (Currently Amended) A process meter as set forth in ~~either of the preceding claims~~ claim 1 wherein the vibrated vibration absorber (60) has a quality factor,  $Q_D$ , which is lower than a quality factor,  $Q_G$ , of the vibrating electronics case (30).

4. (Currently Amended) A process meter as set forth in ~~any one of the preceding claims~~ claim 1 wherein the vibrated vibration absorber (60) has a quality factor,  $Q_D$ , in the range of 1 to 5, particularly on the order of 3.

4. 5. (Currently Amended) A process meter as set forth in ~~any one of the preceding claims~~ claim 1 wherein the vibration absorber (60) has a resonant frequency,  $f_D$ , which differs from a resonant frequency,  $f_G$ , of the electronics case (30) by about 10% at the most.

5. 6. (Currently Amended) A process meter as set forth in ~~any one of the preceding claims~~ claim 1 wherein the vibration absorber (60) has a resonant frequency,  $f_D$ , which is less than a resonant frequency,  $f_G$ , of the electronics case (30).

6. 7. (Currently Amended) A process meter as set forth in ~~any one of the preceding claims~~ claim 1 wherein the vibration absorber (60) has a mass,  $m_D$ , which is greater than 1% of a mass,  $m_G$ , of the electronics case (30).

7. 8. (Currently Amended) A process meter as set forth in ~~any one of the preceding claims~~ claim 1 wherein the vibration absorber (60) is disposed within the electronics case (30).

8. 9. (Currently Amended) A process meter as set forth in ~~any one of the preceding claims~~ claim 1 wherein the vibration absorber (60) comprises a disk- or cup-shaped plastic body (61) having a, particularly disk- or plate-shaped, metal body (62) fitted or embedded therein.

9: 10. (Currently Amended) A process meter as set forth in ~~any one of the preceding claims~~ claim  
1 wherein the vibration absorber (60) comprises a plastic body (61) which is affixed to the wall  
(31) of the electronics case (30), particularly with adhesive.